Inventor: Jon P. Daley

Title: Methods of Forming Patterned Photoresist Layers Over Semiconductor Substrates

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: _9-5-03_   Attorney: _____
                            Mark S. Matkin
                            Reg. No. 32,268

Form PTO-1449 , ,	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2380	SERIAL NO. Unknown
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT: Jon P. Daley	
		FILING DATE Filed Herewith	GROUP Unknown

U.S. PATENT DOCUMENTS

*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,156,674	12/05/00	Li et al.			
	AB	6,281,100 B1	08/28/01	Yiin et al.			
	AC	6,291,363 B1	09/18/01	Yin et al.			
	AD	6,380,611 B1	04/30/02	Yin et al.			
	AE	6,383,723 B1	05/07/02	Iyer et al.			
	AF	10/177,056		Tran			06/21/2002
	AG	10/609,311		Yates			06/26/03
	AH						
	AI						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ							
	AK							
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AM		
	AN		
	AO		

EXAMINER	DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.